

Notice of References Cited		Application/Control No.	Applicant(s)/Patent Under Reexamination	
		10/603,976	JUNG ET AL.	
Examiner		Art Unit	Stephen W. Smoot	
		2813	Page 1 of 1	

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,436,834 B1	08-2002	Lee et al.	438/693
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

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	N	JP 2001085375 A	03-2001	Japan	TSUN-HO et al.	H01L 21/304
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Suzumura et al., "Composition for Polishing," English Translation of JP 11-80708 A, JPO, March 26, 1999.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.